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PATENT NUMBER and
ISSUE DATE

U.S. UTILITY Patent Application

APPL NUM 10007119	FILING DATE 10/26/2001	CLASS 424 424	SUBCLASS 099	GAU 1751	EXAMINER <i>Chen</i>
**APPLICANTS: Uchiyama Kiyoshi; Solayappan Narayan; Paz de Araujo Carlos;					
**CONTINUING DATA VERIFIED:					
** FOREIGN APPLICATIONS VERIFIED:					
PG-PUB <input type="checkbox"/> DO NOT PUBLISH <input type="checkbox"/>		RESCIND <input type="checkbox"/>			
Foreign priority claimed <input type="checkbox"/> yes <input type="checkbox"/> no		35 USC 119 conditions met <input type="checkbox"/> yes <input type="checkbox"/> no		ATTORNEY DOCKET NO	
Verified and Acknowledged Examiners's initials		13249.348			
TITLE : Chemical vapor deposition method of making layered superlattice materials using trimethylbismuth					

U.S. DEPT. OF COMM./PAT. & TM.-PTO-425L (Rev. 12-94)

NOTICE OF ALLOWANCE MAILED		Assistant Examiner	CLAIMS ALLOWED	
			Total Claims	Print Claim for O.G.
ISSUE FEE		Primary Examiner	DRAWING	
Amount Due	Date Paid		Sheet to Drawg.	Figs. Drawg.
<input type="checkbox"/> TERMINAL DISCLAIMER		PREPARED FOR ISSUE	Application Examiner	
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